

Model : NC-80MAP

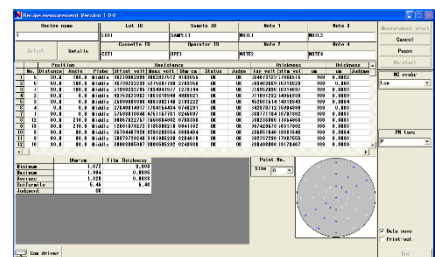
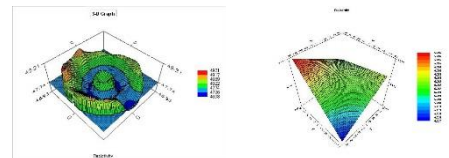
Non-contact sheet resistance measurement system



The NC-80MAP measures sheet resistance for Epi materials(GaAs ,GaN, SiC wafers) and metal layer etc. without contacting (Eddy current measurement method). It provides high accuracy/high tact measurement. And also it can expand to fully automatic system with robot and cassette station.

Feature and function

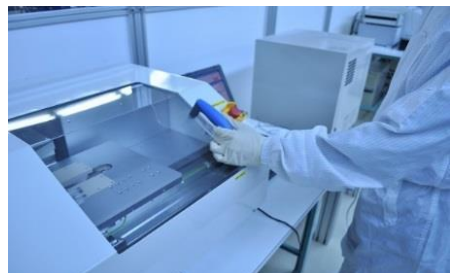
- *Multi-points measurement and Mapping display (and 2-D map / 3-D map graphic display with maximum 217 points)
- *Wide ranges measurement and high accuracy with Non-contact eddy current probes
- *Mapping program software
 - Arranged in a concentric multipoint pattern measurement is programmed (maximum 217 points) and random pattern is programmable by operator.
 - SPC charts and 2-D, 3-D mapping software.
 - SPC chart function includes Ave, Max, Min and each limit(Upper/Lower control and setting), and Uniformity (% , Standard deviation)
- *Wafer load/unload function and the aligner unit.
- *2 to 8 inch wafer measurement is available
- *Easy operation by Windows 10 system software
- *Measurement data base link with Excel via CSV format file



Specifications

*Option : Up to 13,000 ohm/sq with Napson reference wafers

Probe type	Measurement Range
(1) Super Low	0.005 ~ 0.01 ohm/sq
(2) Low	0.01 ~ 0.5 ohm/sq
(3) Middle	0.5 ~ 10 ohm/sq
(4) High / Super High	10 ~ 3200 ohm/sq



*Diameter of probe cores : 14 mm diameter (5 mm is available : S-Low, Low)

A global leading company for resistivity measurement system.



Measurement accuracy performance

Conforms to ASTM F673.

The data is driven using NIST or VLSI wafers with manually placed on probing unit and 1.7 to 2 mm gap.

Linearity (Less than)

Measurement Range	%
0.005 ~ 0.01 ohm/sq	± 2 %
0.01 ~ 0.05 ohm/sq	± 2 %
0.05 ~ 10 ohm/sq	± 2 %
10 ~ 1000 ohm/sq	± 2 %
1000 ~ 3200 ohm/sq	± 3 %

Repeatability

*CV = STDEV/P/AVG × 100%(Typical)
Repeatability by each ohm/sq (% of one sigma) and 10 times measurement (same site of the certified area of NIST and/or VLSI standards).

Measurement Range	%
0.005 ~ 0.01 ohm/sq	0.1 %
0.01 ~ 0.05 ohm/sq	0.1 %
0.05 ~ 10 ohm/sq	0.1 %
10 ~ 1000 ohm/sq	0.2 %
1000 ~ 3200 ohm/sq	0.7 %

Throughput (Tact time)

*The time is estimated with ϕ 200 mm" wafers. Measurement tact is 0.1s/point.

Points	Line	Circle (Points)
5	18s(± 1s)	18s(± 1s)
9	18s(± 2s)	19s(± 2s)
17	33s(± 2s)	39s(± 2s)
37	48s(± 3s)	57s(± 3s)
49	66s(± 3s)	77s(± 3s)
121	93s(± 3s)	130s(± 3s)
217	138s(± 5s)	208s(± 5s)
☆ Please visit our website for the movie of this system		

*Please contact us for more details.

*The customers are always welcome to do a demo measurement.

*Specification subject to change without notice.